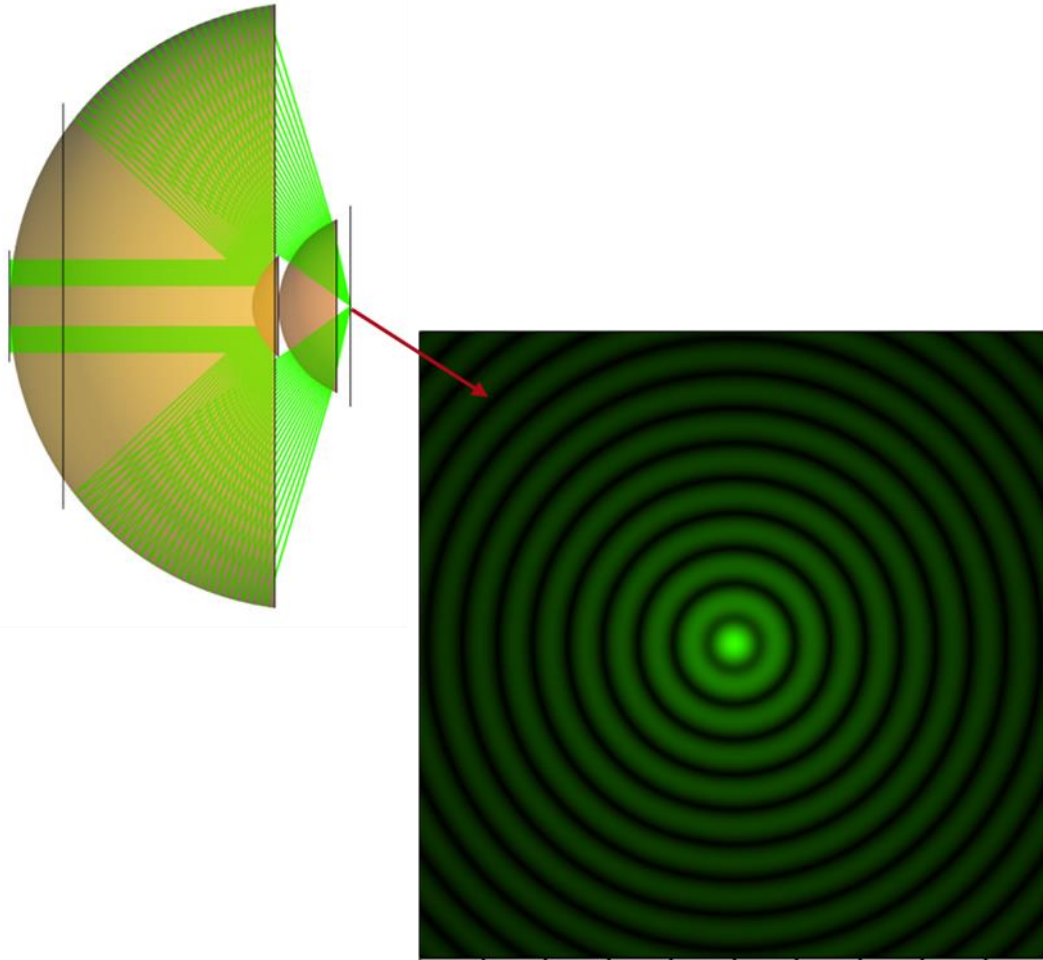


# Reflecting Microscope System with very high Numerical Aperture

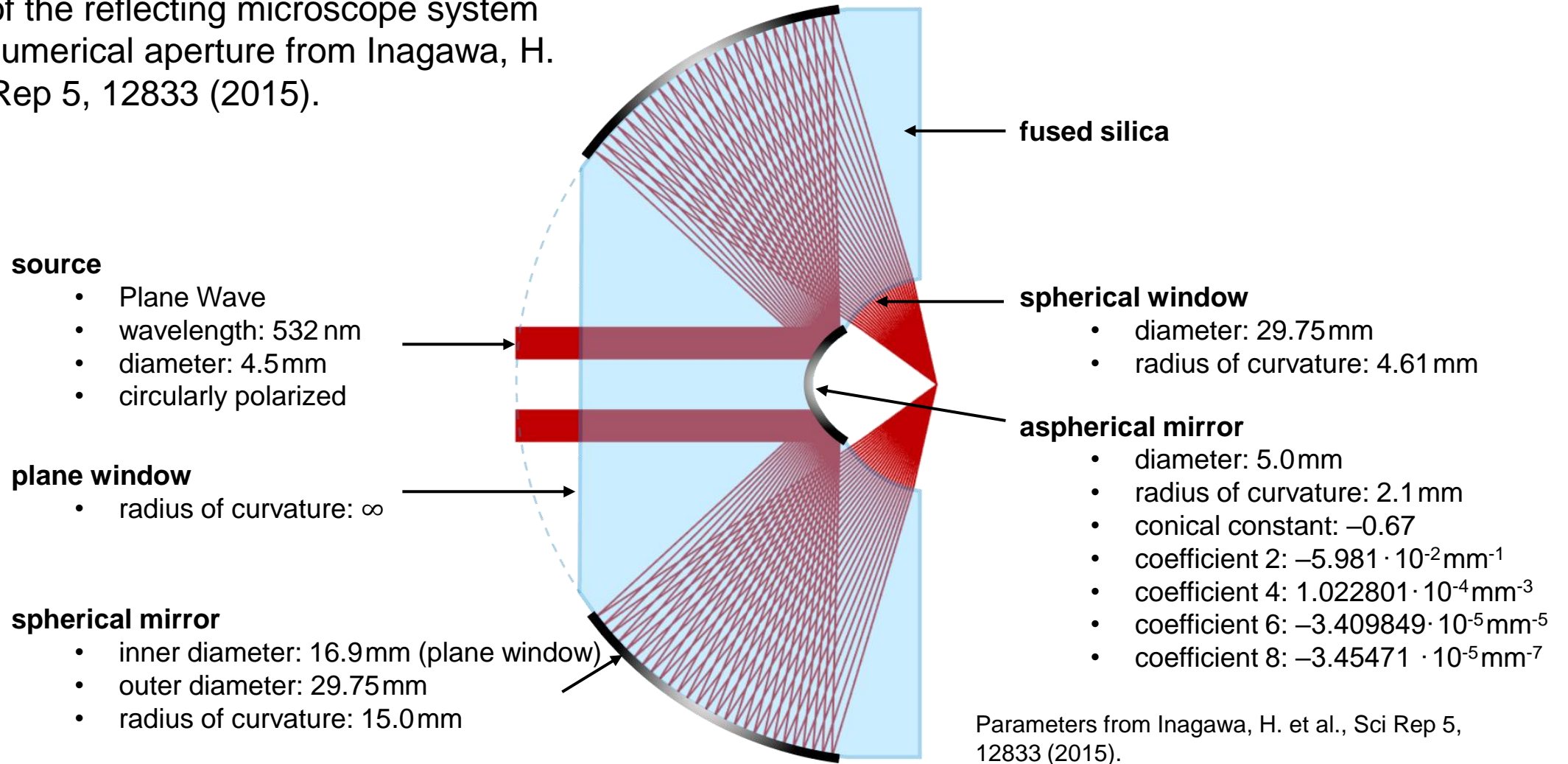
# Abstract



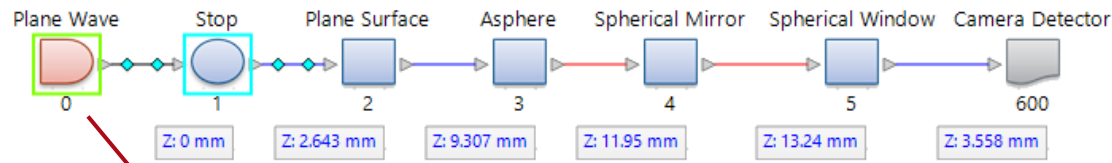
In single-molecule microscopy imaging applications, localization precision is a critical issue. Since the localization precision in a certain direction is proportional to the width of the point spread function (PSF) of the image in the same direction, a microscope with a higher numerical aperture (NA) can reduce the width of the PSF and thus improve the localization precision. In this use case, we demonstrate the modeling of very compact reflecting microscope system with an NA of 0.99 (Inagawa et al., 2015), and compare the results obtained with VirtualLab Fusion's fast physical optics technology to the reference.

# Task Description

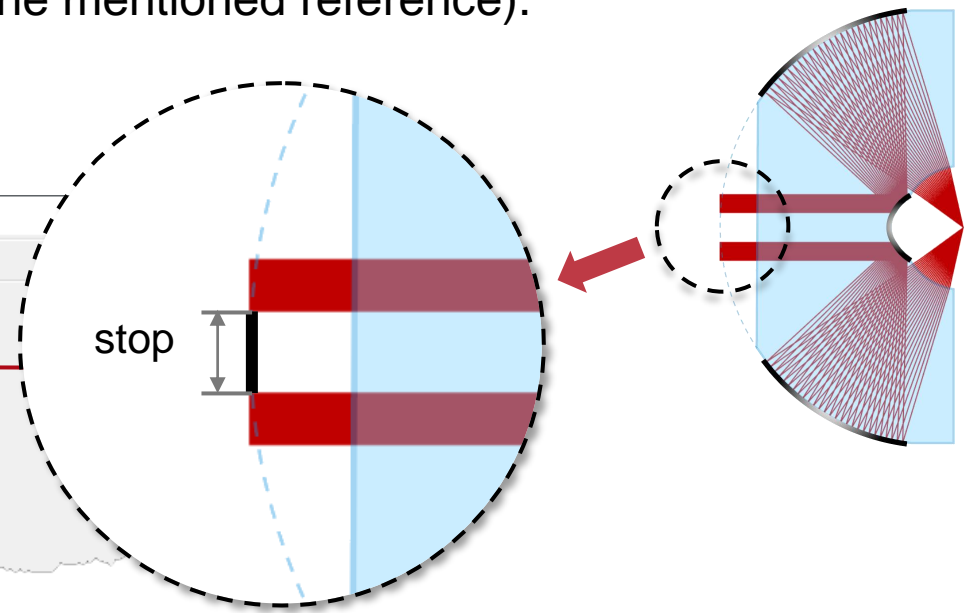
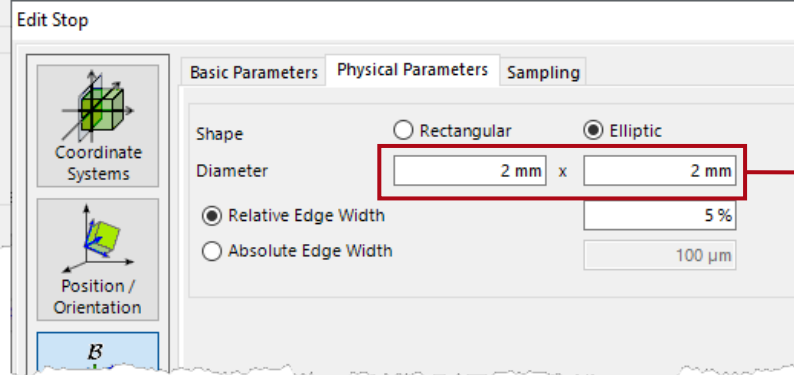
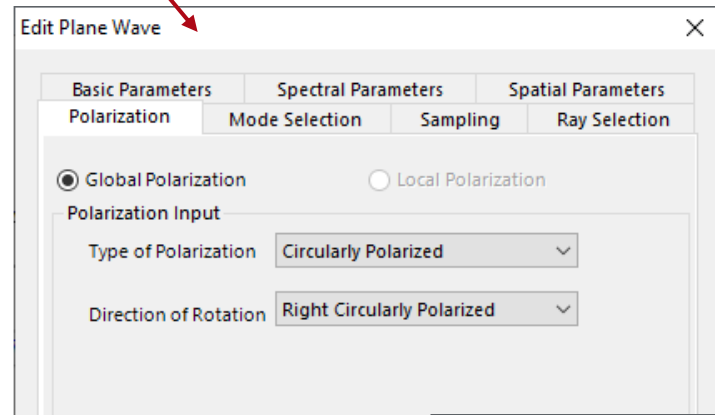
Modeling of the reflecting microscope system with high numerical aperture from Inagawa, H. et al., Sci Rep 5, 12833 (2015).



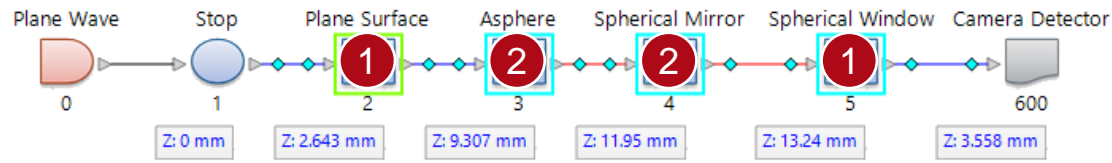
# System Building Blocks – Source



- In order to avoid additional effects introduced by an asymmetrical polarization state, the input plane wave is circularly polarized (right-hand oriented).
- An additional *Stop* component is applied to block light that would be reflected by the aspheric mirror but never reach the spherical mirror (as shown in the mentioned reference).



# System Building Blocks – Objective Lens

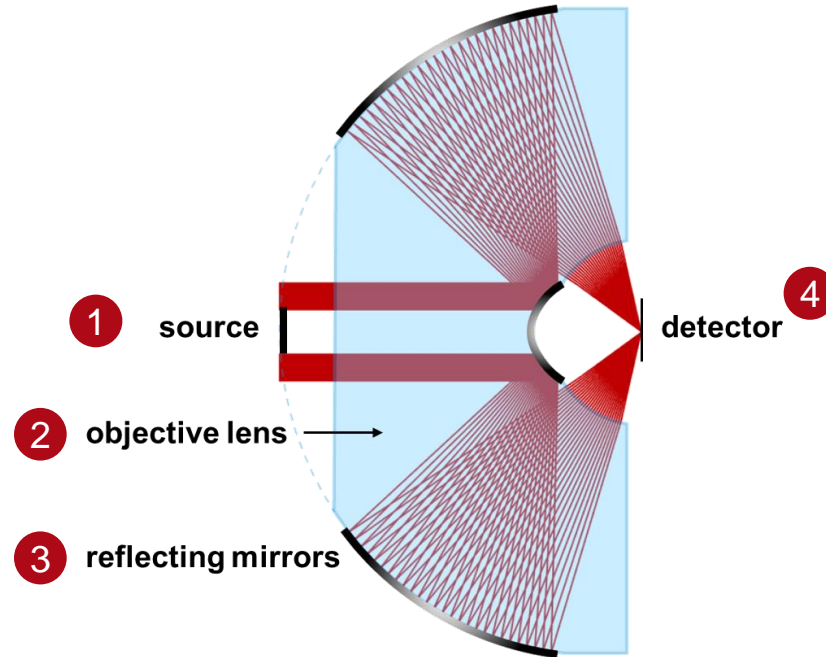


The complex and partially coated lens consists of two parts: 1. the fused silica lens component itself and 2. the ideally reflecting coatings that provide the aspherical and spherical mirror functions.

This section shows a detailed view of the lens component, labeled '1'. It features a blue semi-circular lens with a red rectangular 'plane window' on the left and a red rectangular 'spherical window' on the right. Below the lens are two software interface windows. The 'Edit Plane Surface Component' window shows a 20 mm x 20 mm component size, 'Plane Surface' specification, and 'Fused\_Silica in Homogeneous Medium' as the medium behind the surface. The 'Edit Curved Surface Component' window shows 'Spherical Window' specification and 'Air in Homogeneous Medium' as the medium behind the surface.

This section shows a detailed view of the coatings, labeled '2'. It features a blue semi-circular lens with a red rectangular 'aspherical mirror' coating on the top surface and a red rectangular 'spherical mirror' coating on the bottom surface. Below the lens are two software interface windows. The top 'Edit Curved Surface Component' window shows 'Aspherical Surface' specification and 'Ideal High Reflectance Material in Homogeneous Medium' as the medium behind the surface. The bottom 'Edit Curved Surface Component' window shows 'Spherical Mirror' specification and 'Ideal High Reflectance Material in Homogeneous Medium' as the medium behind the surface.

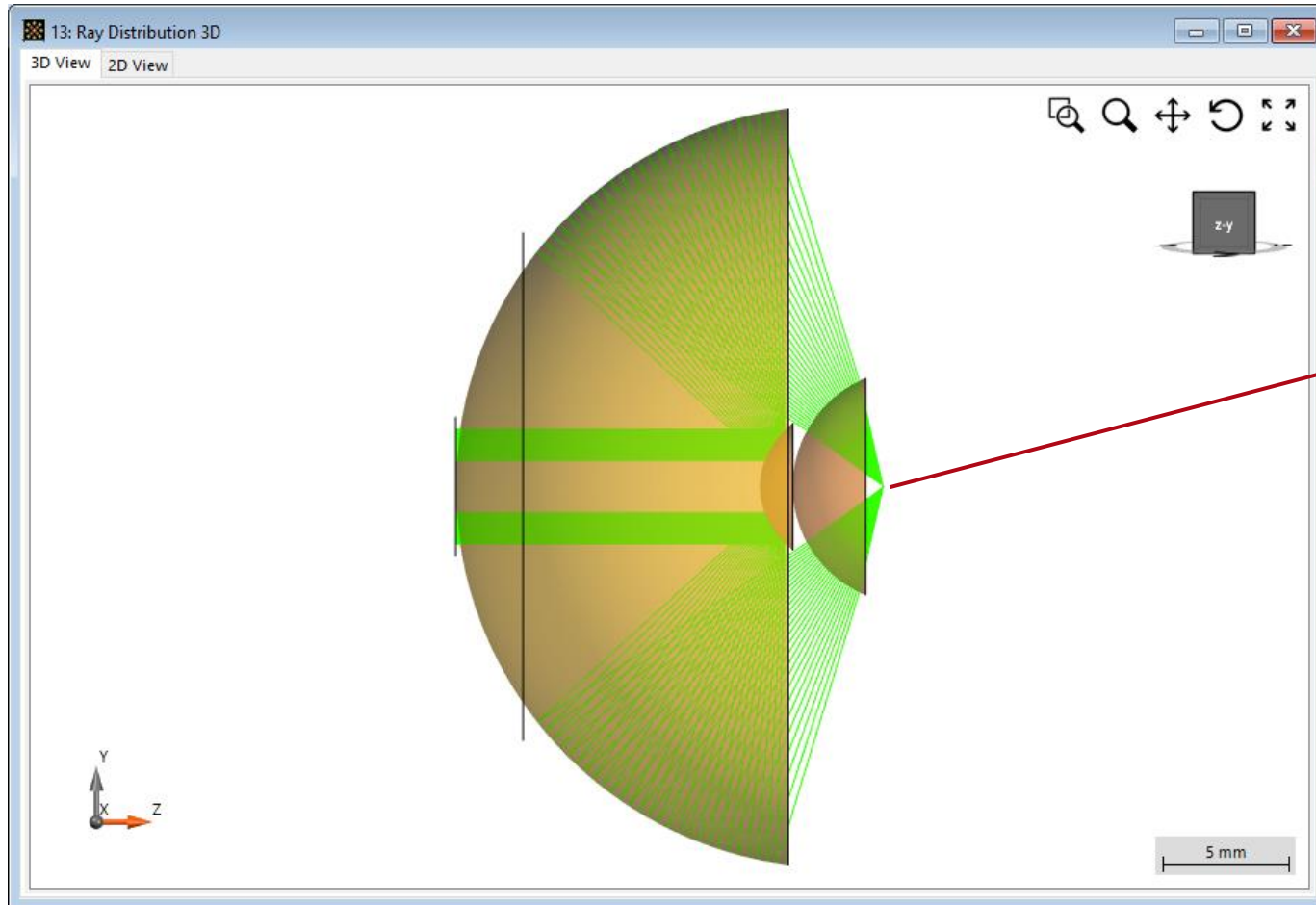
# Summary of Model



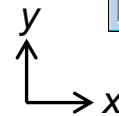
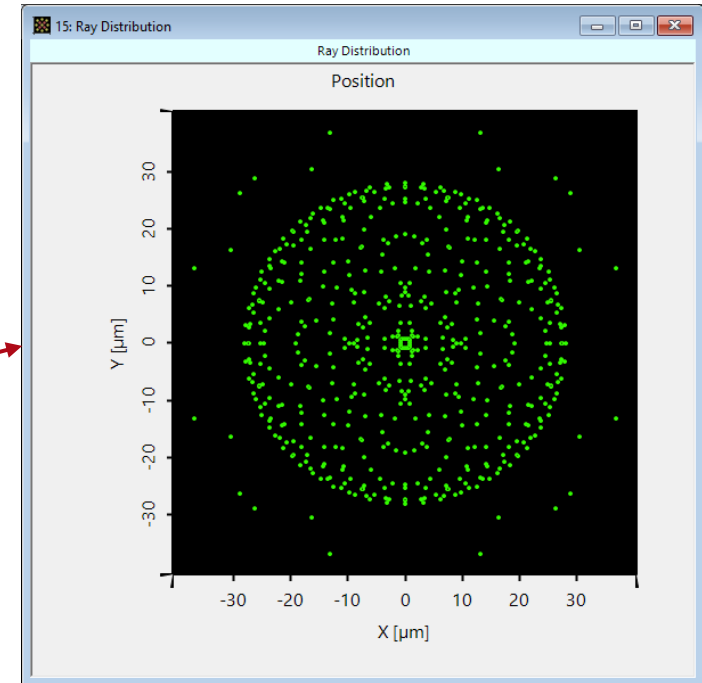
Optical System	Elements in VirtualLab Fusion	Model/Solver/Detected Value
1. source	<i>Plane Wave source &amp; Stop</i>	truncated ideal plane wave
2. objective lens	<ul style="list-style-type: none"> <li>• <i>Plane Surface</i></li> <li>• <i>Conical Surface</i></li> </ul>	<ul style="list-style-type: none"> <li>• Fresnel Matrix</li> <li>• Local Plane Interface Approximation</li> </ul>
3. reflecting mirrors	<i>Conical Surface</i>	Local Plane Interface Approximation
4. detector	<i>Camera Detector</i>	energy density measurement

# Ray Tracing Result

rays in system:

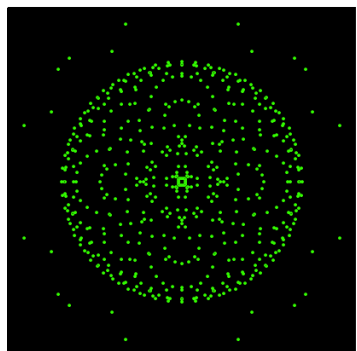
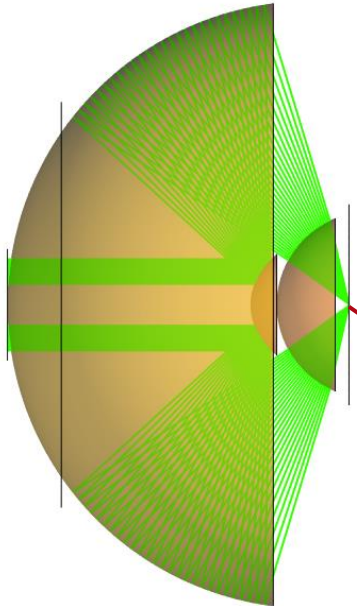


ray distribution on detector plane:

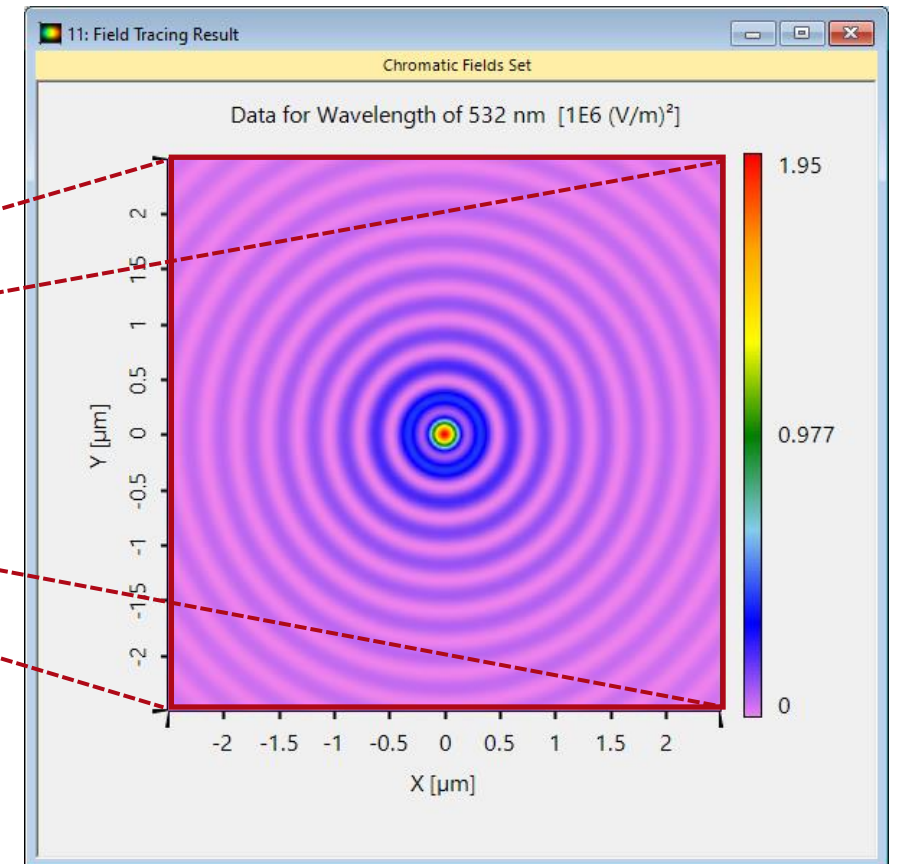
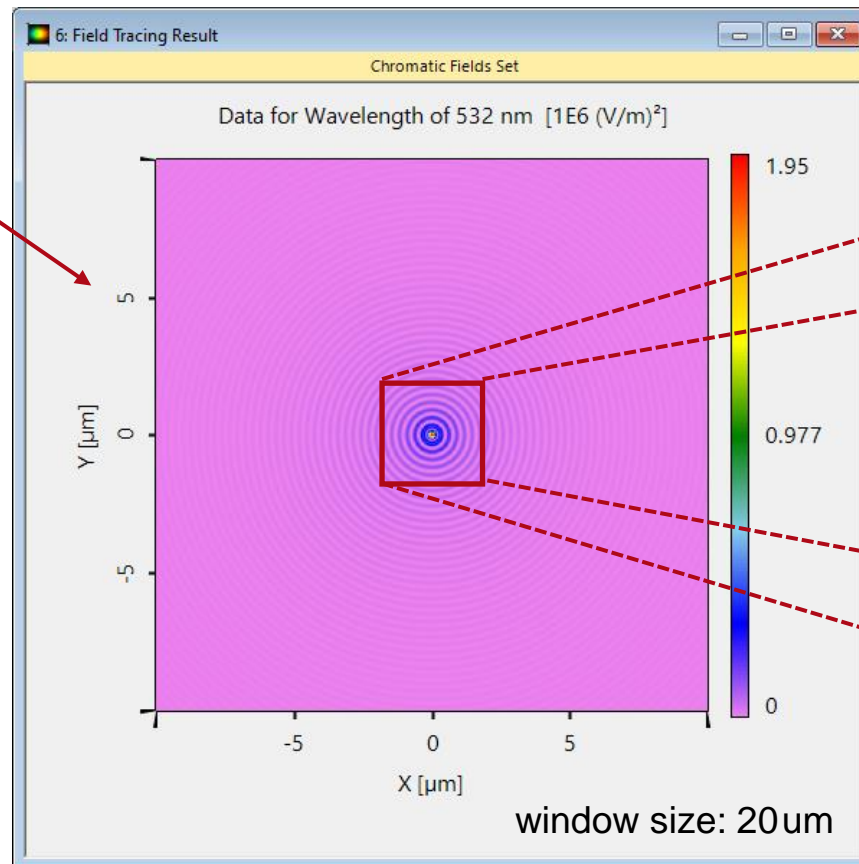


# Result: Field Tracing (False Color)

The width of the PSF is much smaller than the diameter obtained in the ray tracing spot diagram due to the strong diffraction effects introduced by the very high NA.

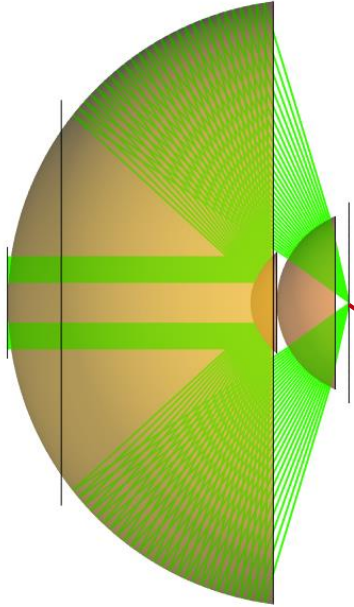


window size: 80um

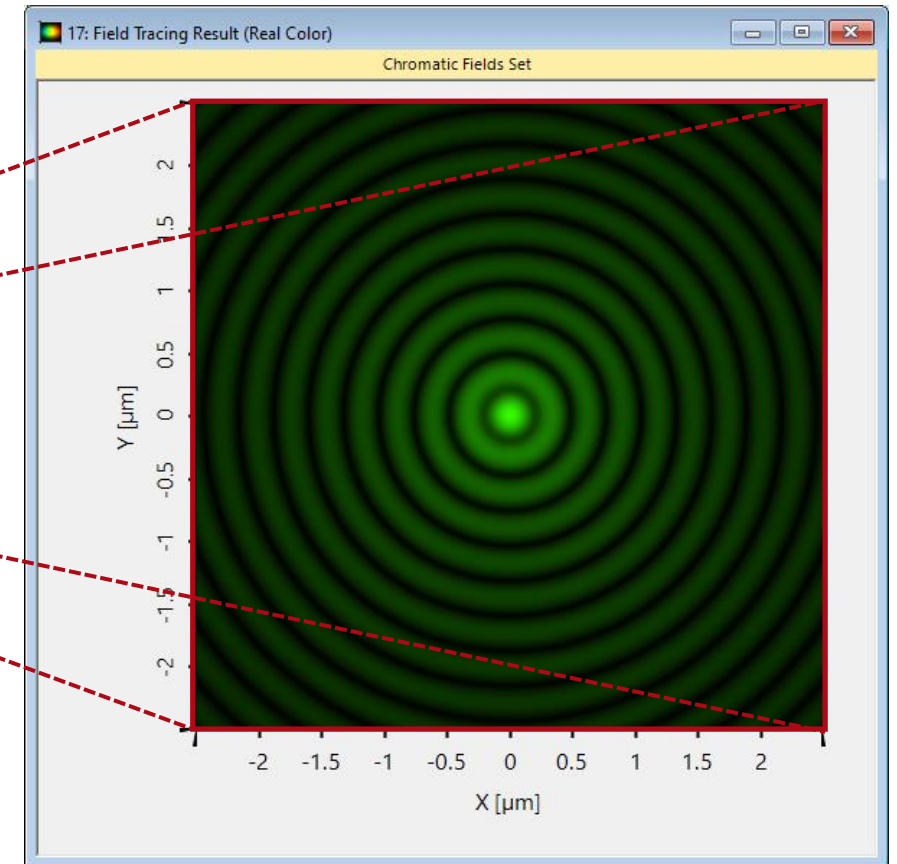
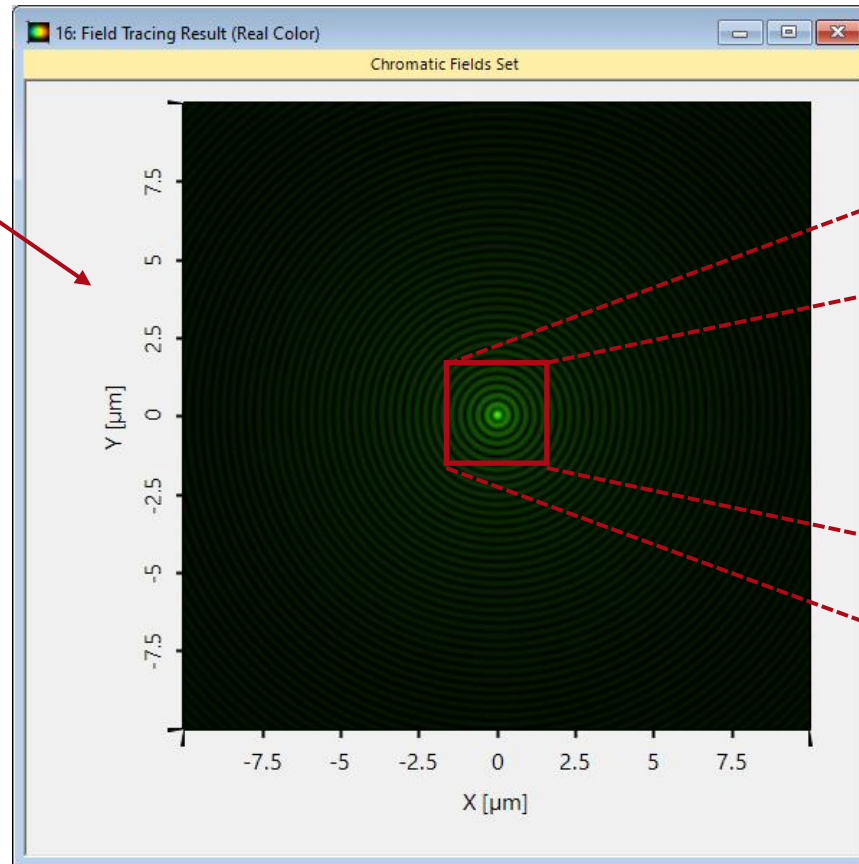




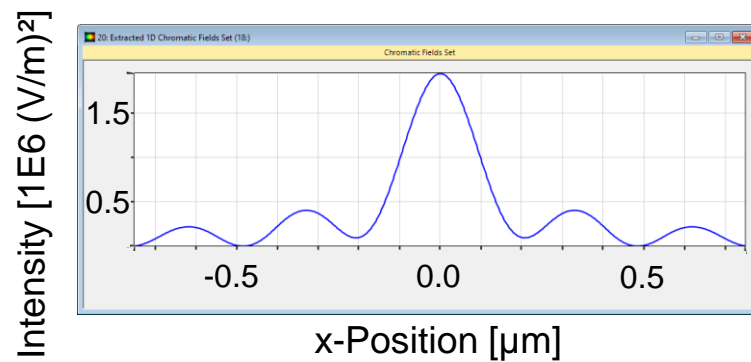
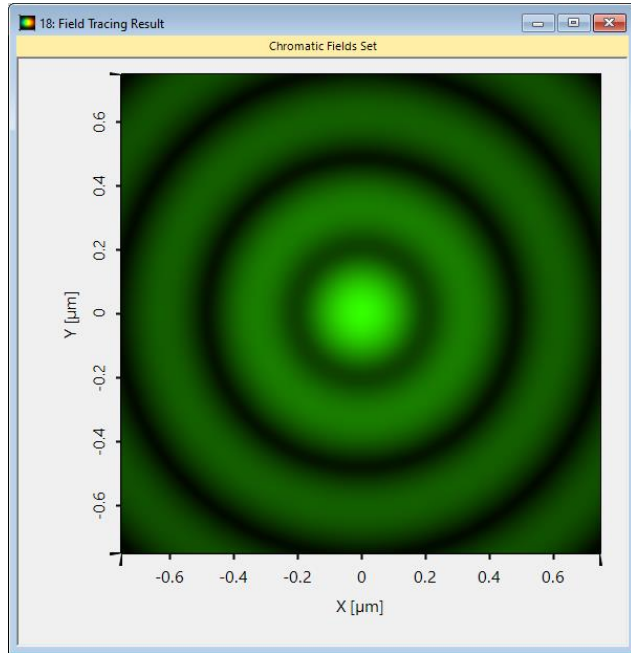
# Result: Field Tracing (Real Color)



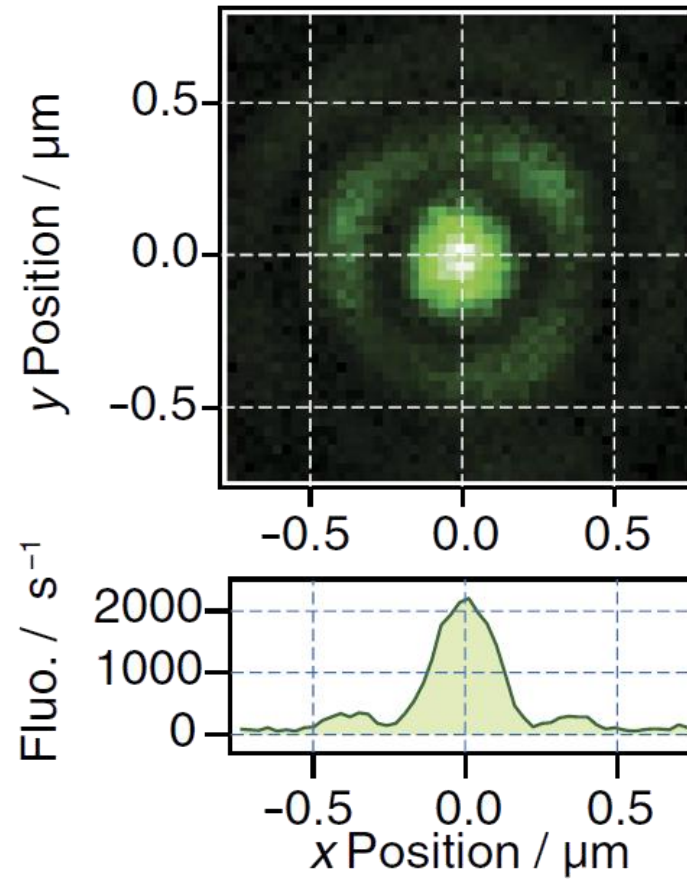
The width of the PSF is much smaller than the diameter obtained in the ray tracing spot diagram due to the strong diffraction effects introduced by the very high NA.



# Comparison with Experimental Results

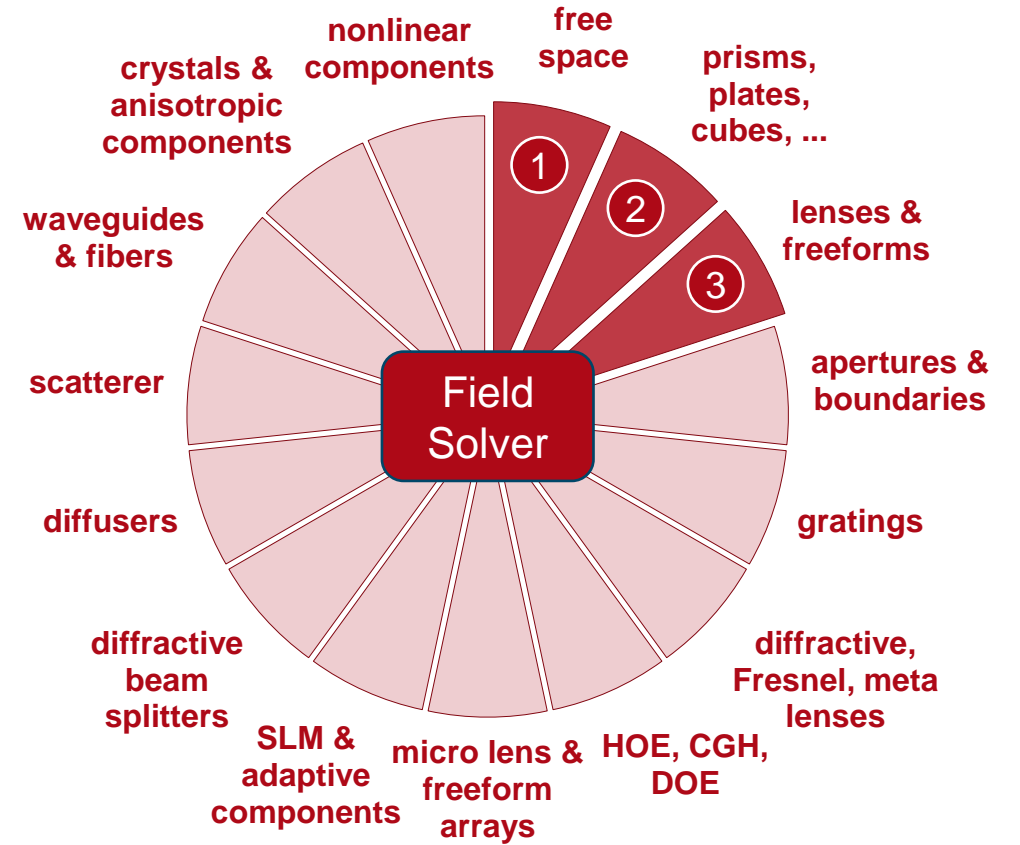
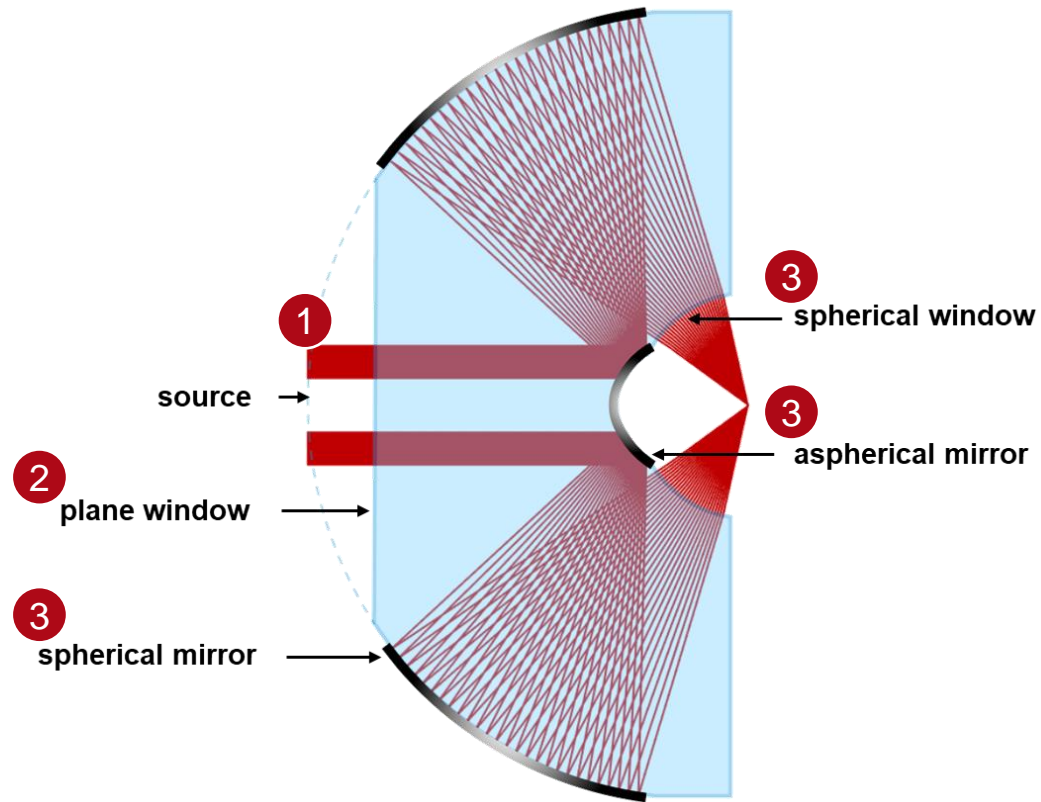


NA = 0.99,  $\lambda_{\text{ex}} = 532 \text{ nm}$



Experimental measurements from Inagawa, H. et al., Sci Rep 5, 12833 (2015).

# VirtualLab Fusion Technologies



# Document Information

title	Reflecting Microscope System with very high Numerical Aperture
document code	MIC.0022
document version	1.0
software edition	VirtualLab Fusion Basic
software version	2021.1 (Build 1.180)
category	Application Use Case
further reading	<ul style="list-style-type: none"><li>- <a href="#"><u>Analysis of Off-Axis Imaging by a High-NA Microscope</u></a></li><li>- <a href="#"><u>Analysis of PSF of a Dipole Source by a High-NA Microscopy System</u></a></li><li>- <a href="#"><u>Single Molecule Imaging by High-NA Fourier Microscope</u></a></li></ul>